

<b>INFORMATION DISCLOSURE STATEMENT</b> PTO-1449 <b>1 P E</b>	Atty. Docket No.: 030865	Serial No.: 10/619,192
	Applicants: Mamoru NAKASUJI et al.	
	Filing Date: July 15, 2003	Group Art Unit: <sup>2881</sup> Not yet assigned

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### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
<u>KN</u>	AA	6,411,377	Noguchi et al.	06/25/2002	356 237.4	07/28/1999
<u>KN</u>	AB	6,593,152	Nakasuji et al.	07/15/2003	438 14	11/02/2001
<u>KN</u>	AC	5,892,224	Nakasuji	04/06/1999	250 310	05/09/1997, See page 1 in the spec.
_____	AD					
_____	AE					

### FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)
_____ AF			
_____ AG			
_____ AH			
_____ AI			
_____ AJ			

### OTHER DOCUMENTS

<u>KN</u>	AK	Shinada, H. et al. "High Speed and Large-Current Electron Optics for Wafer Inspection", Proceedings LSI Testing Symposium/2000 Conference Minutes, pp. 151-156
_____	AL	(English Translation is enclosed (Marked-up Portion Only)., Also see the page 1 in the spec.)
Examiner	<u>lul</u>	Date Considered 10-07-06